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CASE CL/V-31563P1

CERTIFICATE OF MAILING

I hereby certify that this paper (along with any paper referred to as being attached or enclosed) is being deposited with the United States Postal Service on the date shown below with sufficient postage as in class mail in an envelope addressed to the:

Jennifer China

Type or print name

Signature Signature

November 11, 2003

Date

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF QIU ET AL.

APPLICATION NO: 09/911,218

FILED: JULY 23, 2001

FOR: PROCESS FOR SURFACE MODIFYING SUBSTRATES AND

MODIFIED SUBSTRATES RESULTING THEREFROM

Commissioner for Patents PO Box 1450 Alexandria, VA 22313-1450

FEE LETTER FOR INFORMATION DISCLOSURE STATEMENT

Sir:

Please charge Deposit Account No. 19-0134 in the name of Novartis in the amount of \$180 for payment of the fee pursuant to 37 CFR §1.17(p) for the submission of an Information Disclosure Statement under 37 CFR §1.97(c).

An additional copy of this paper is here enclosed. The Commissioner is hereby authorized to charge any additional fees which may be required, or credit any overpayment, to Account No. 19-0134 in the name of Novartis.

Respectfully submitted,

Jian Zhou

Agent for Applicants

Reg. No. 41,422

Novartis Pharmaceuticals Corporation Patent and Trademark Dept. One Health Plaza East Hanover, NJ 07936-1080

(678) 415-4691

Date: November 11, 2003

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Jennifer China

Type or print name

Signaturé

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INFORMATION DISCLOSURE STATEMENT

Sir:

This Information Disclosure Statement is being filed in accordance with 37 C.F.R. §1.97(c). A letter for payment of fee set forth in 37 C.F.R. §1.17(p) is enclosed.

In accordance with 37 C.F.R. §1.56, applicants wish to call the Examiner's attention to the references cited on the attached form(s) PTO-1449.

Copies of these references are enclosed herewith.

01 FC:1806

The Examiner is requested to consider the foregoing information in relation to this application and indicate that each reference was considered by returning a copy of the initialed PTO 1449 form(s).

Respectfully submitted,

Agent for Applicants

Reg. No. 41,422

Novartis Pharmaceuticals Corporation Patent and Trademark Dept. One Health Plaza East Hanover, NJ 07936-1080 (678) 415-4691

Date: November 11, 2003

FORM PTO-1449 (REV. 7-85) U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE

INFORMATION DISCLOSURE CITATION

(Use several sheets if necessary)

ATTY. DOCKET NO. CL/V-31563P1 APPLICATION NO. 09/911,218 APPLICANT QIU ET AL. FILING DATE JULY 23, 2001

Group

U.S. PATENT DOCUMENTS

XAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE
	AA	US 6, 020,175	2/1/00	Onda et al	435/	180	9/10/97
	AB						
	AC						
	AD						
	AE.	:					1
	AF						IZIT
	AG						7 2 5
	АН						7
	Al						70 8
	AJ						0 5
	AK						
	AL						

FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	OFFICE	CLASS	SUBCLASS	TRAN YES	SLATION NO			
	АМ										
	AN										
	AO										
	AP										
	AQ										
	AR	Patterned Polymer Multilayer Fabrication By Controlled Adhesion Of Polyelectrolytes To Plasma- Modified Fluoropolymer Surfaces By Vargo, Calvert, Wynne, Avlyanov, MacDiarmid, & Rubner 1966.									
	AR	Patterned Polymer Multilayer Fabrication By Controlled Adhesion Of Polyelectrolytes To Plasma-Modified Fluoropolymer Surfaces By Vargo, Calvert, Wynne, Avlyanov, MacDiarmid, & Rubner 1966. Molecular Self Assembly of Conducting Polymers: A New Layer-By-Layer Thin Flim Deposition									
	AS	Process. By Cheung, Fou, Ferrira, & Rubner. MIT									
•	АТ										
EXAMI	EXAMINER			DATE CONSIDERED		<u> </u>		<u>-</u>			

*EXAMINER: Initial of reference considered, whether or not citation is in conformance with MPEP 609: Draw a line through citation if not in conformance and not considered. Include a copy of this form with the next communication to applicant.